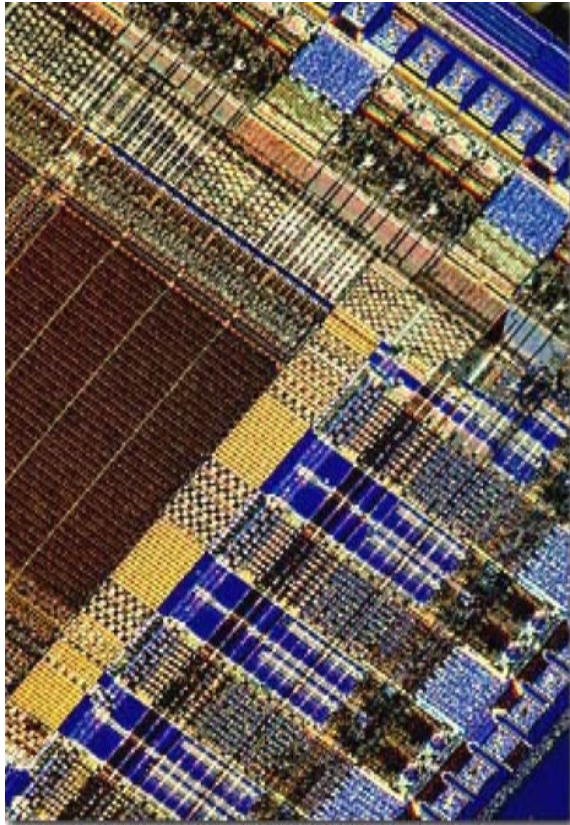


CMOS Digital Integrated Circuits

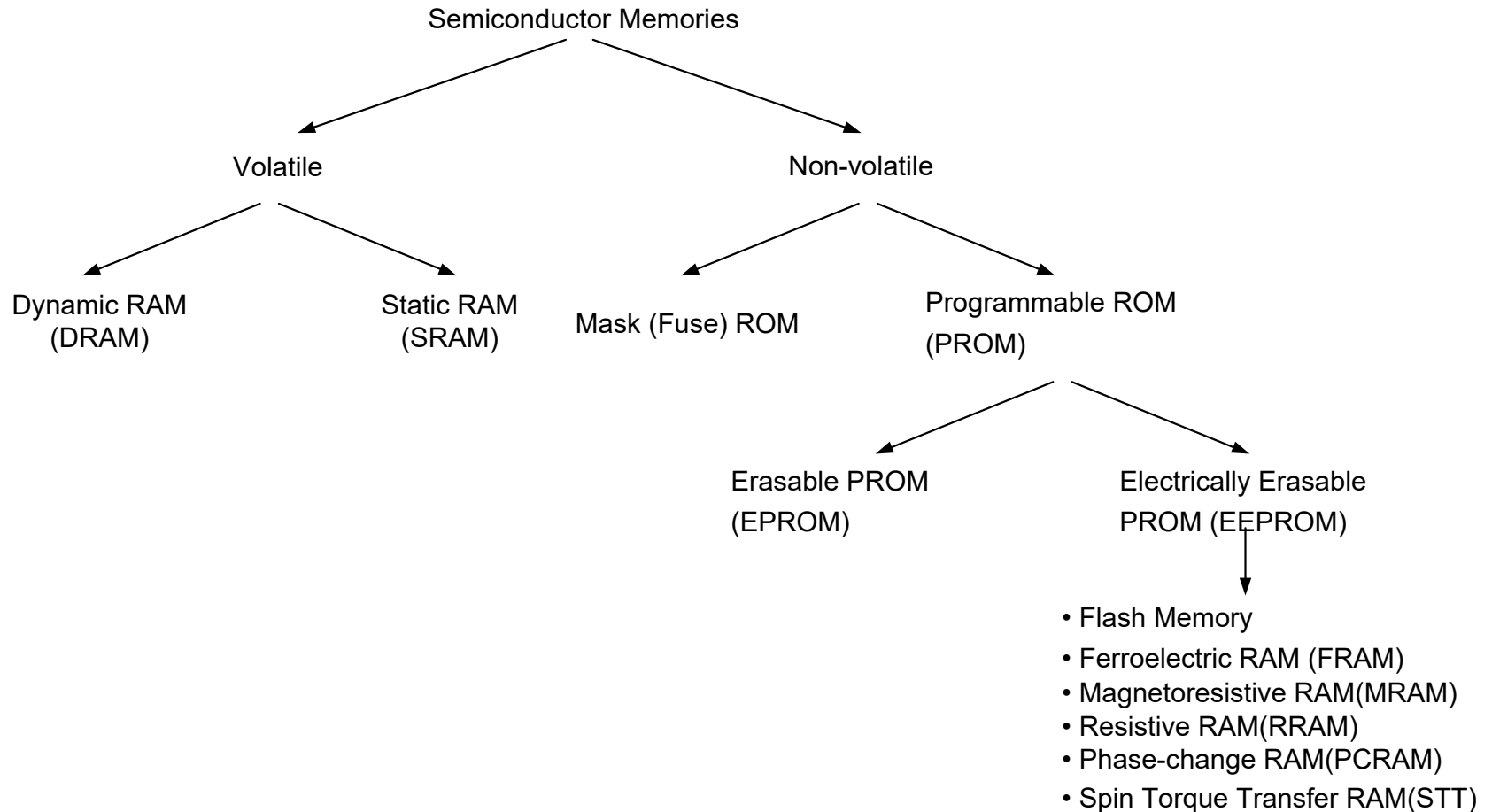


Chapter 10 Semiconductor Memories

S.M. Kang, Y. Leblebici, and
C. Kim

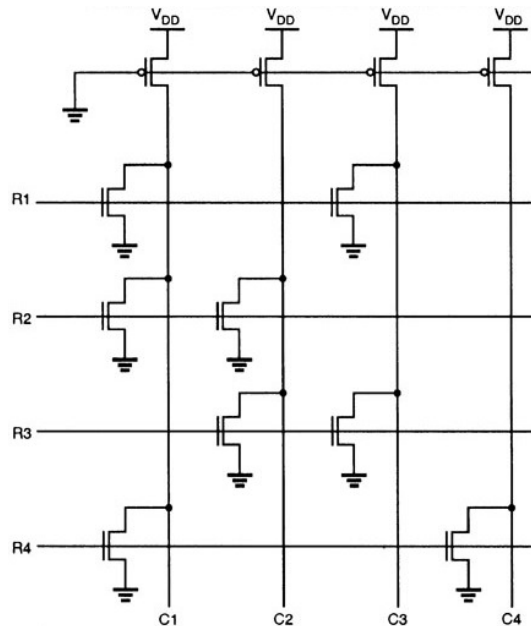
10.1 Introduction

◆ Semiconductor memory types



10.4 Nonvolatile Memory

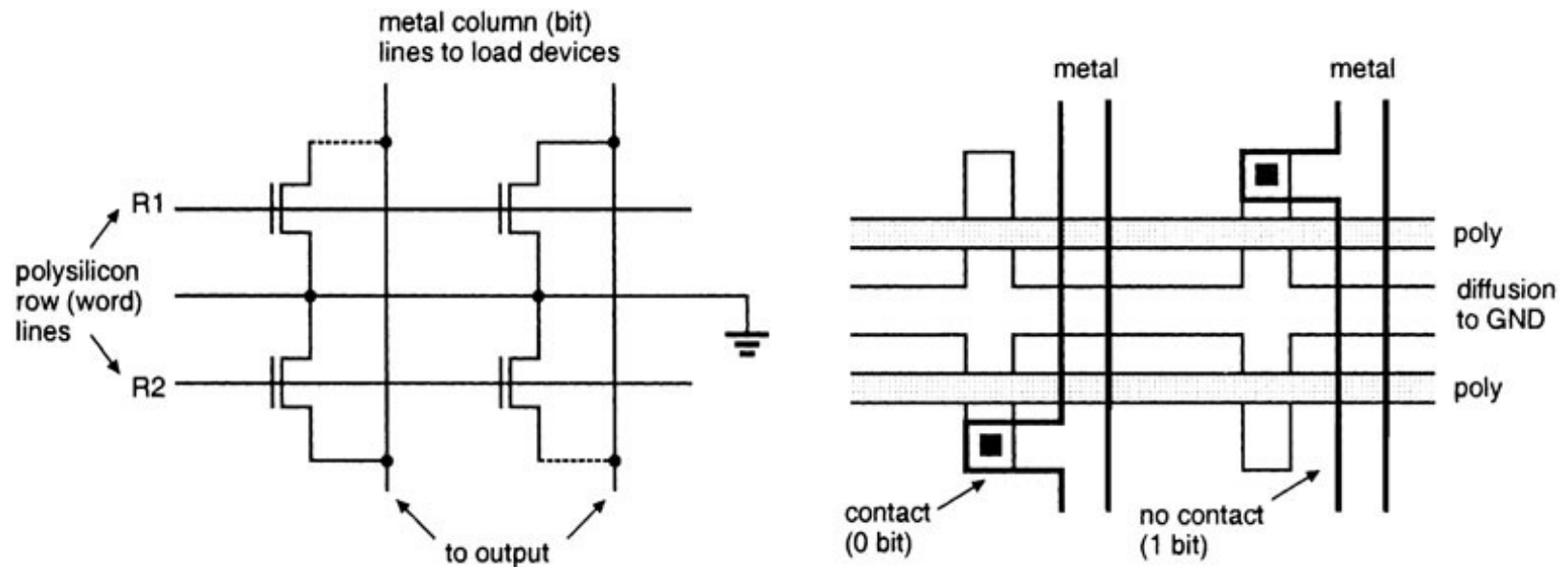
- ◆ Simple combinational Boolean network
- ◆ Only one word line selected at a time
- ◆ Active transistors exist at cross point
- ◆ Dynamic ROM
 - use periodic precharge signal to reduce static power



R1	R2	R3	R4	C1	C2	C3	C4
1	0	0	0	0	1	0	1
0	1	0	0	0	0	1	1
0	0	1	0	1	0	0	1
0	0	0	1	0	1	1	0

Layout of NOR ROM Array(1)

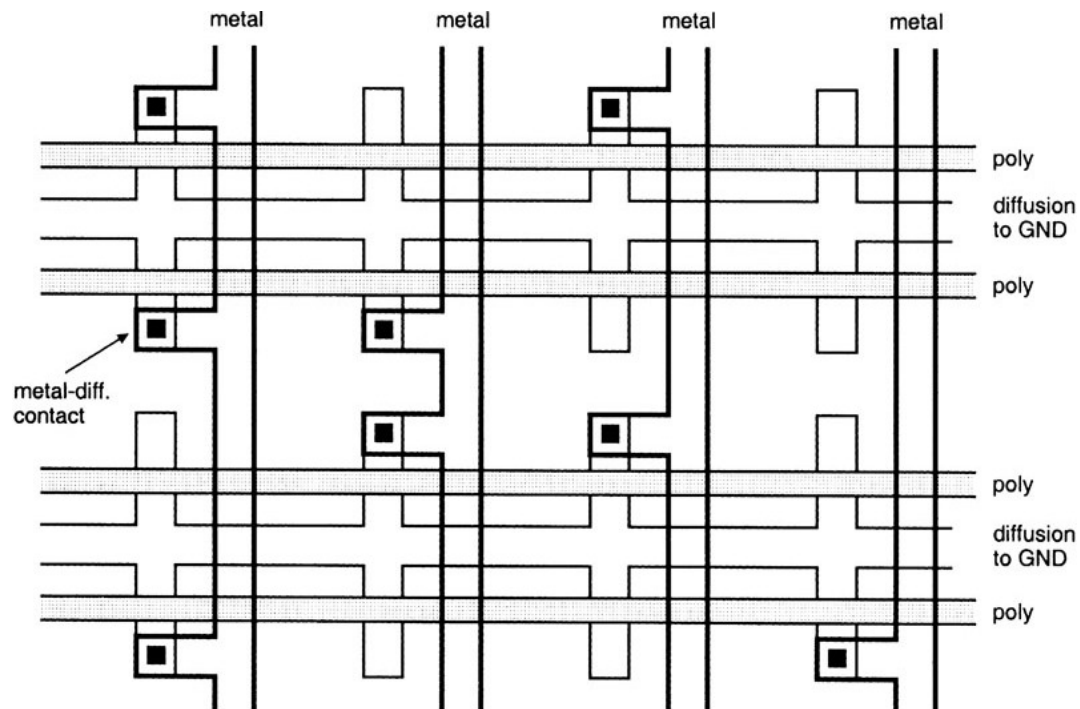
- ◆ Initially, NMOS at every row-column intersection
- ◆ '1'-bits are realized by omitting drain or source connection or gate electrode of corresponding NMOS



Layout example of a NOR ROM array

Layout of NOR ROM Array(2)

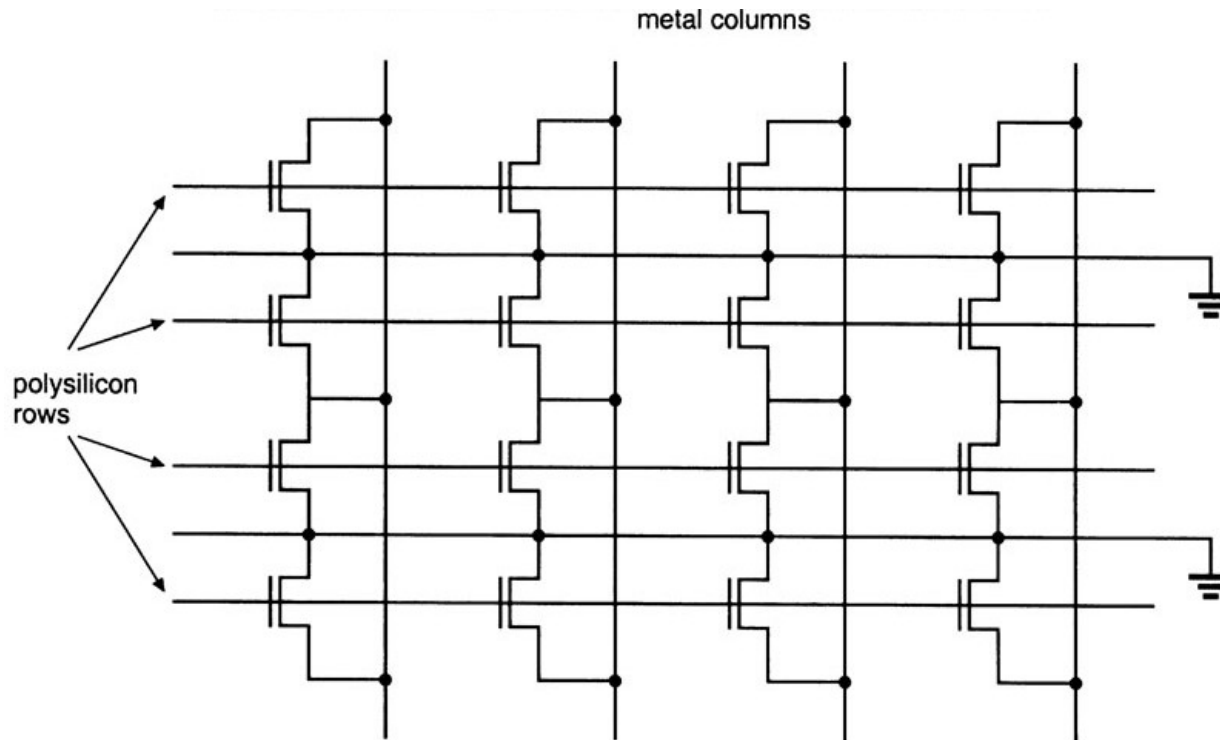
- ◆ In reality, metal column lines laid out directly on top of diffusion column to reduce horizontal dimension



Layout of the 4-bit X 4-bit NOR ROM array (pp. 46)

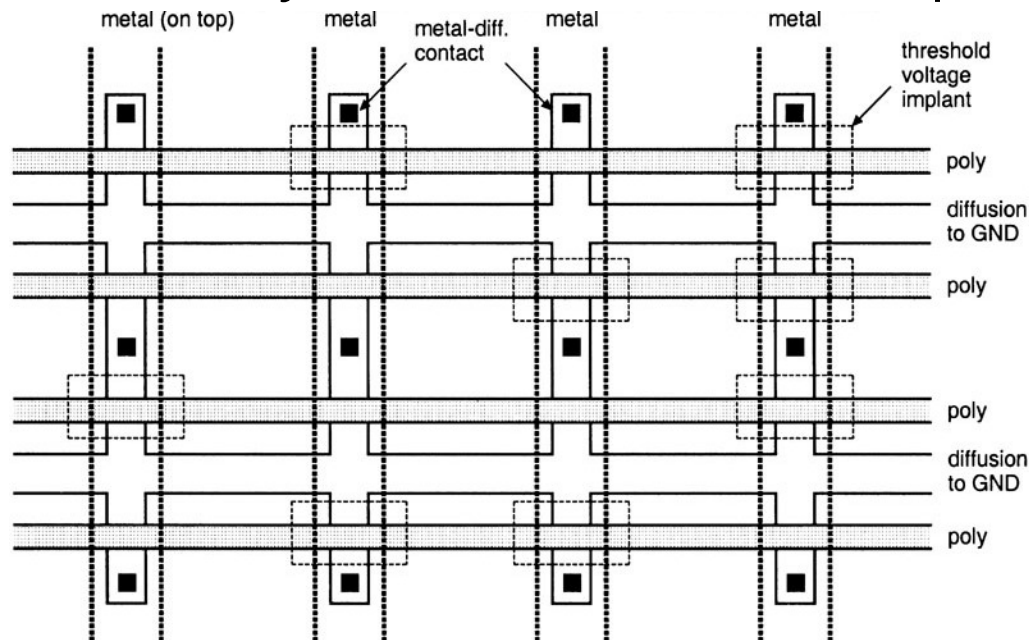
Implant-mask Programmable NOR ROM

- ◆ Every two rows share a common ground connection
- ◆ Every metal to diffusion contact shared by two adjacent devices



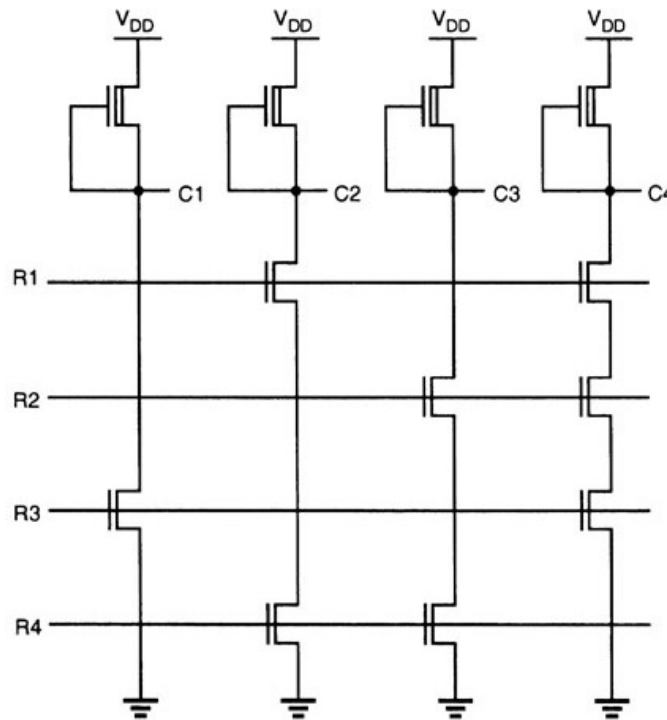
4-bit x 4-bit NOR ROM Array

- ◆ Based on implant-mask programming
- ◆ Raised threshold voltage $> V_{OH}$ \rightarrow "1"-bit
- ◆ Non-implanted \rightarrow "0"-bit
- ◆ higher core density (smaller silicon area per stored bit)



4-bit x 4-bit NAND ROM Array

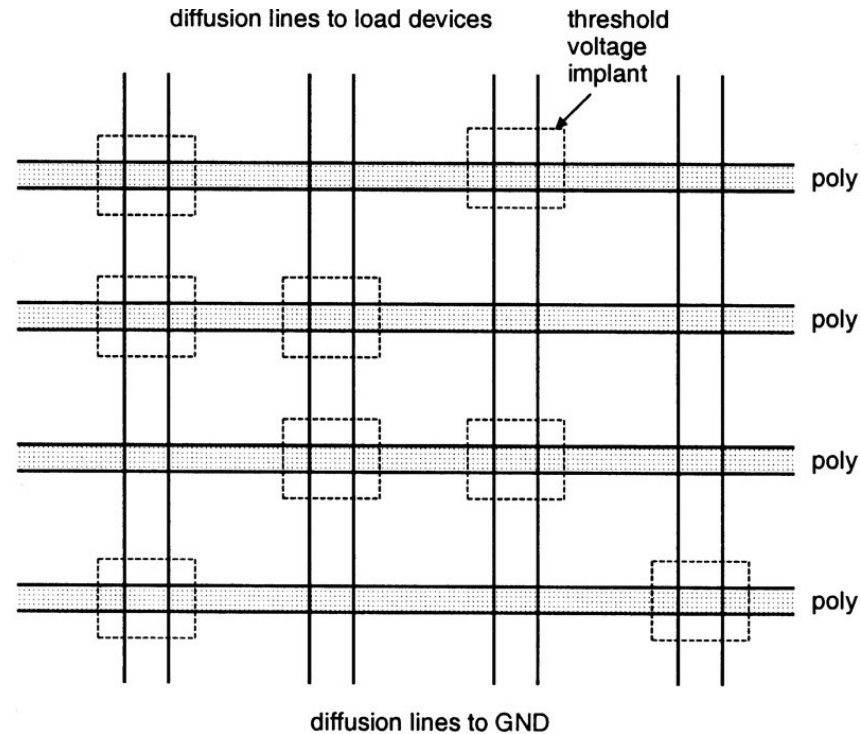
- ◆ Bit line : depletion-load NAND gate
- ◆ Deactivated transistor → "1"-bit
- ◆ Shorted or on transistor → "0"-bit



R1	R2	R3	R4	C1	C2	C3	C4
0	1	1	1	0	1	0	1
1	0	1	1	0	0	1	1
1	1	0	1	1	0	0	1
1	1	1	0	0	1	1	0

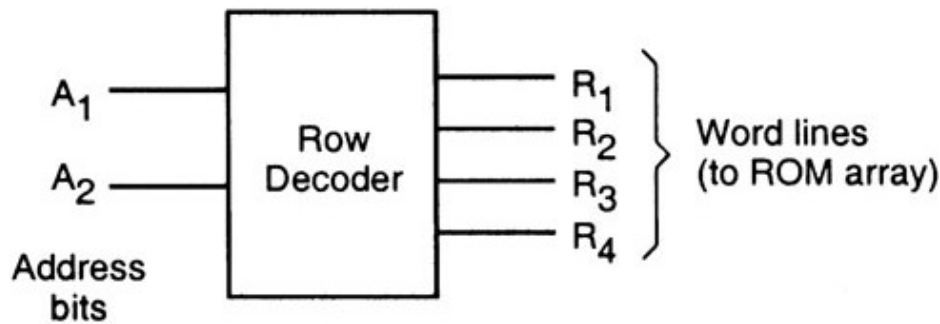
Implant-mask layout of NAND ROM

- ◆ Lowered threshold voltage $< 0V \rightarrow$ "0"-bit
- ◆ Much more compact than NOR ROM
- ◆ Access time is slower than NOR ROM

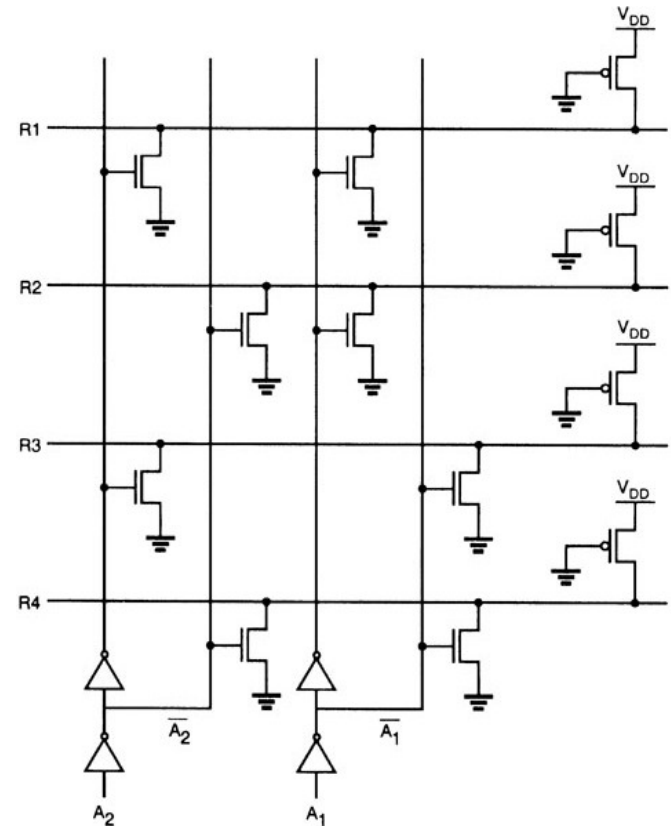


Design of Row and Column Decoders(1)

- ◆ Select a particular memory location in array
- ◆ Row address decoder example

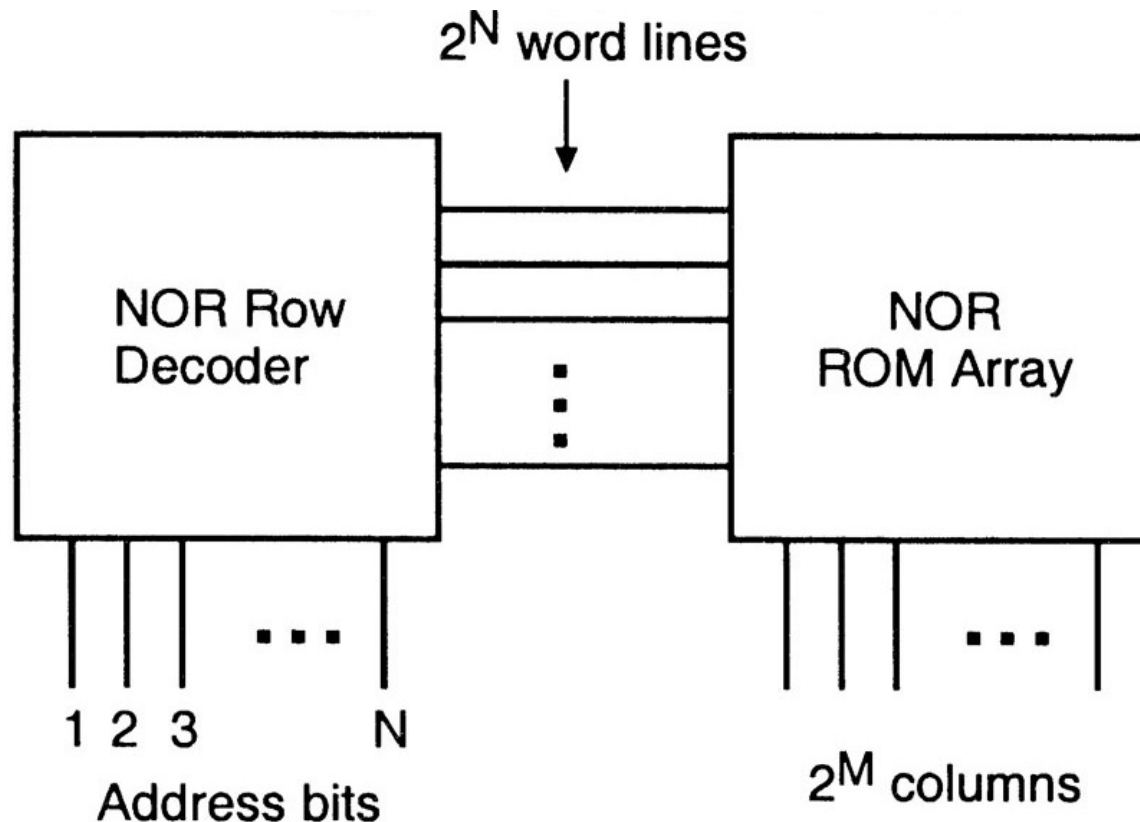


A_1	A_2	R_1	R_2	R_3	R_4
0	0	1	0	0	0
0	1	0	1	0	0
1	0	0	0	1	0
1	1	0	0	0	1



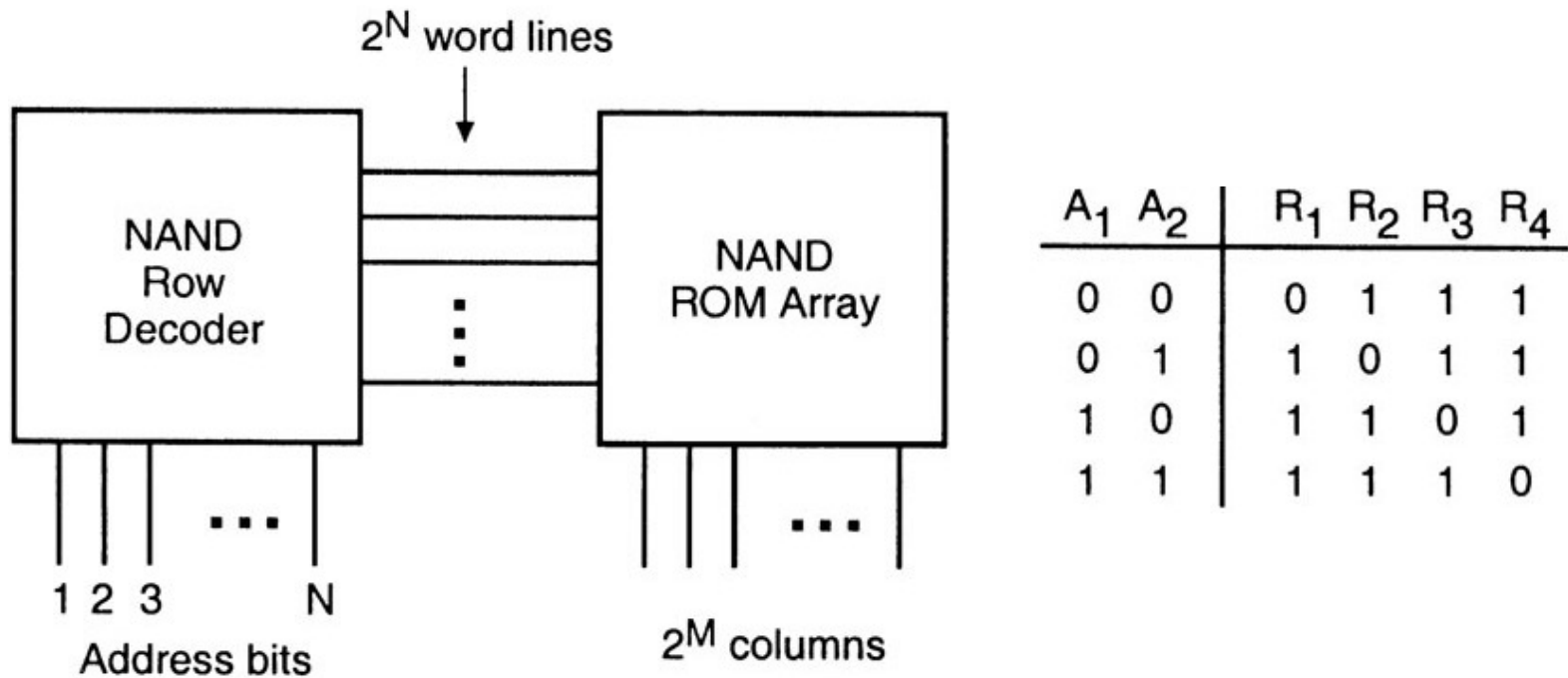
Design of Row and Column Decoders(2)

- ◆ ROM array and row decoder (two adjacent NOR arrays)



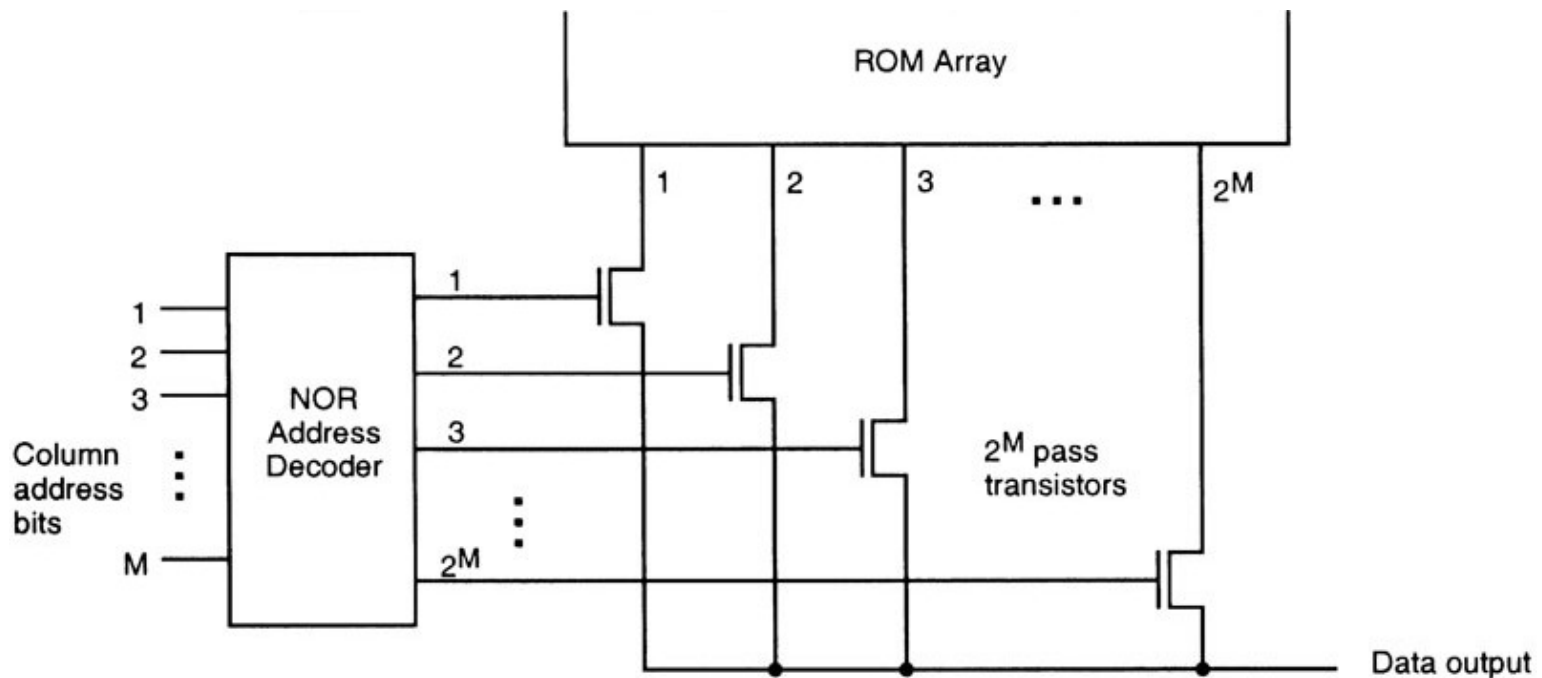
Row Decoder for NAND ROM

- ◆ Lower voltage for logic "0"
- ◆ Realized using same layout strategy as memory array



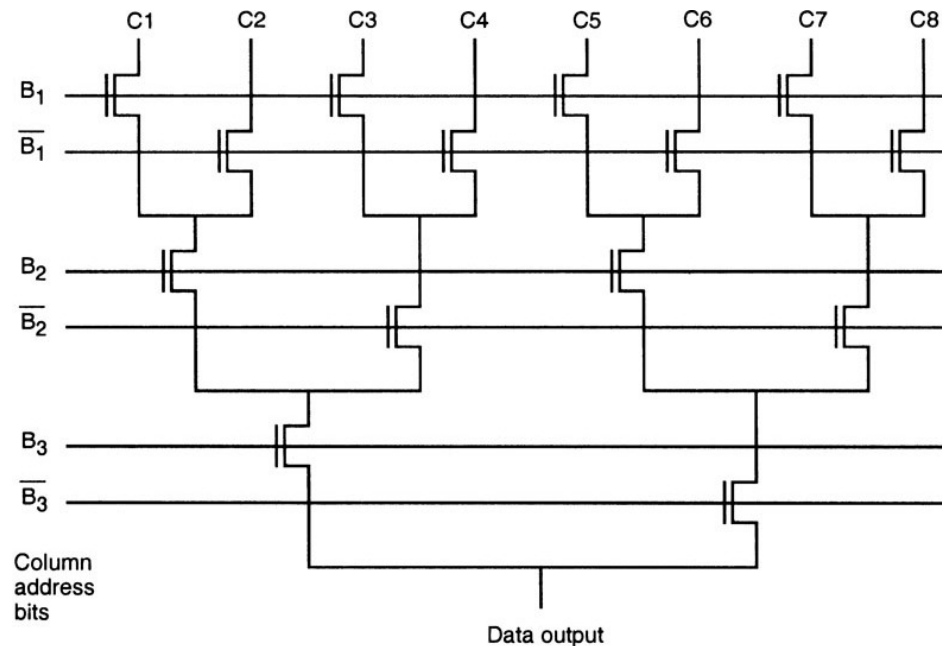
Column Decoder(1)

- ◆ Using NOR address decoder and NMOS pass transistor
- ◆ Only one pass transistor turned on at a time
- ◆ $2^M(M+1)$ transistors required



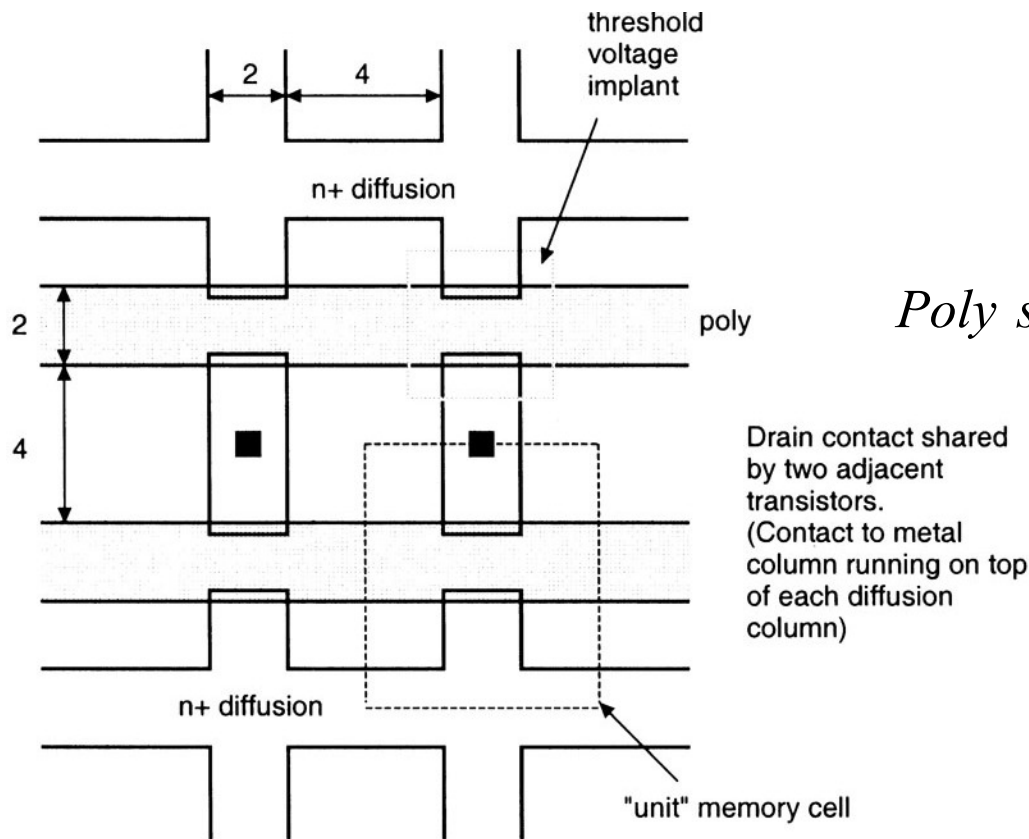
Column Decoder(2)

- ◆ Binary selection tree decoder
- ◆ NOR address decoder not needed
 - ➔ Reduce the number of transistors significantly
- ◆ But, long data access time



Example 10.1(1)

- ◆ Analyze the access time of a 32-kbit NOR ROM array



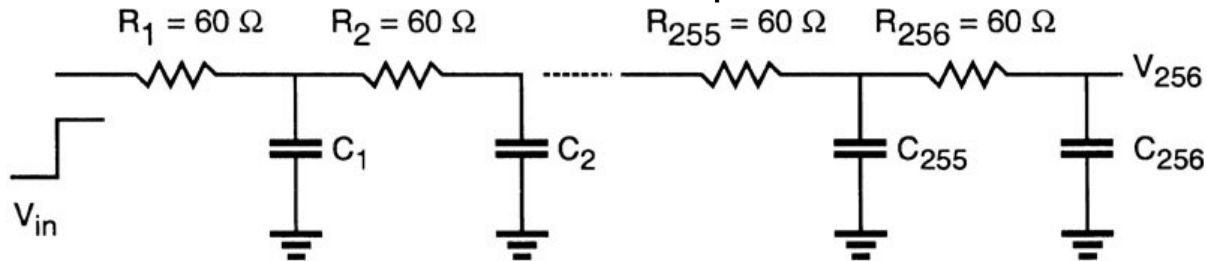
$$\mu_n C_{ox} = 20 \mu A / V^2$$

$$C_{ox} = 3.47 \mu F / cm^2$$

Poly sheet resistance = 20Ω / square

Example 10.1(2)

- Assume 7 row address bits and 8 column address bits (128 rows and 256 columns)
- Calculate row resistance and capacitance



$$C_{row} = C_{ox} \cdot W \cdot L = 10.4 \text{ fF / bit}$$

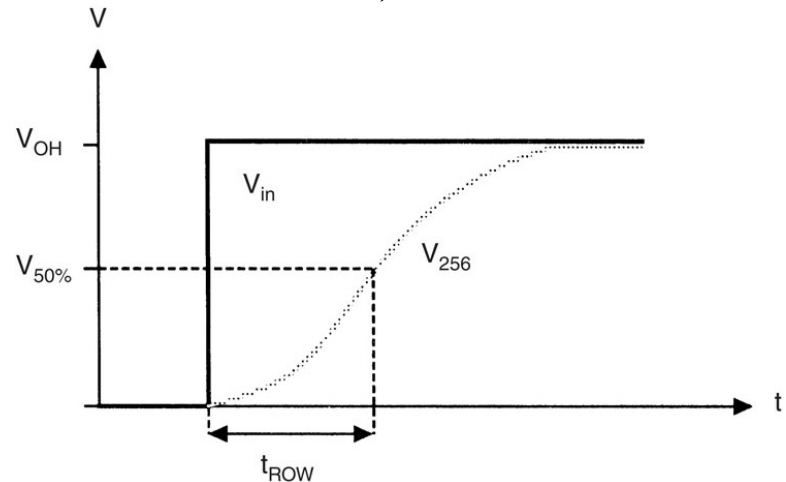
$$R_{row} = (\# \text{ of squares}) \times (\text{Poly sheet resistance}) = 60 \Omega / \text{bit}$$

- Calculate row access time

$$t_{row} \approx 0.38 \cdot R_T \cdot C_T = 15.53 \text{ ns}$$

$$R_T = \sum_{\text{all columns}} R_i = 15.36 \text{ k}\Omega$$

$$C_T = \sum_{\text{all columns}} C_i = 2.66 \text{ pF}$$



Example 10.1(3)

- A more accurate delay: Elmore time constant for RC ladder circuits

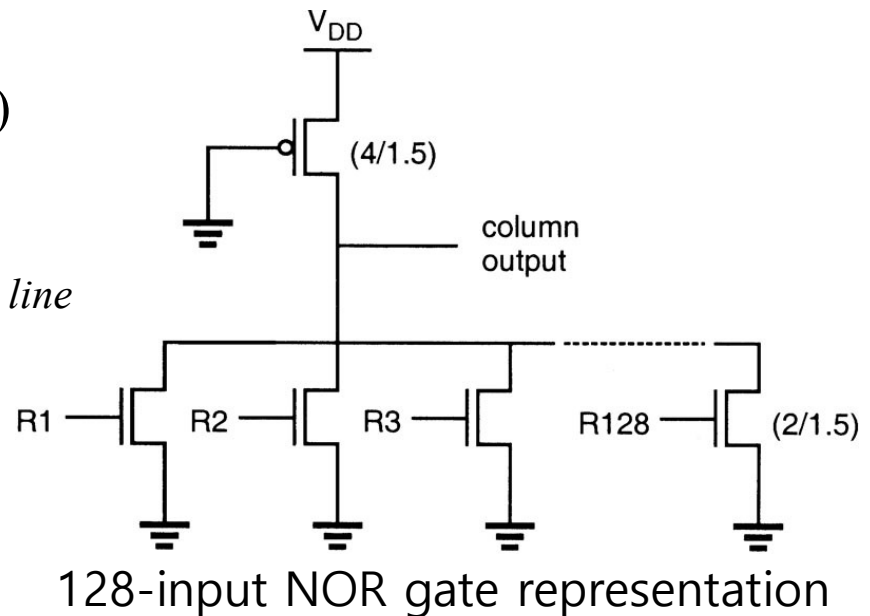
$$t_{row} = \sum_{k=1}^{256} R_{jk} C_k = 20.52ns \quad \text{where} \quad R_{jk} = \sum_{j=1}^k R_j$$

- Calculate column access time

$$C_{column} = 128 \times (C_{gd,driver} + C_{db,driver})$$

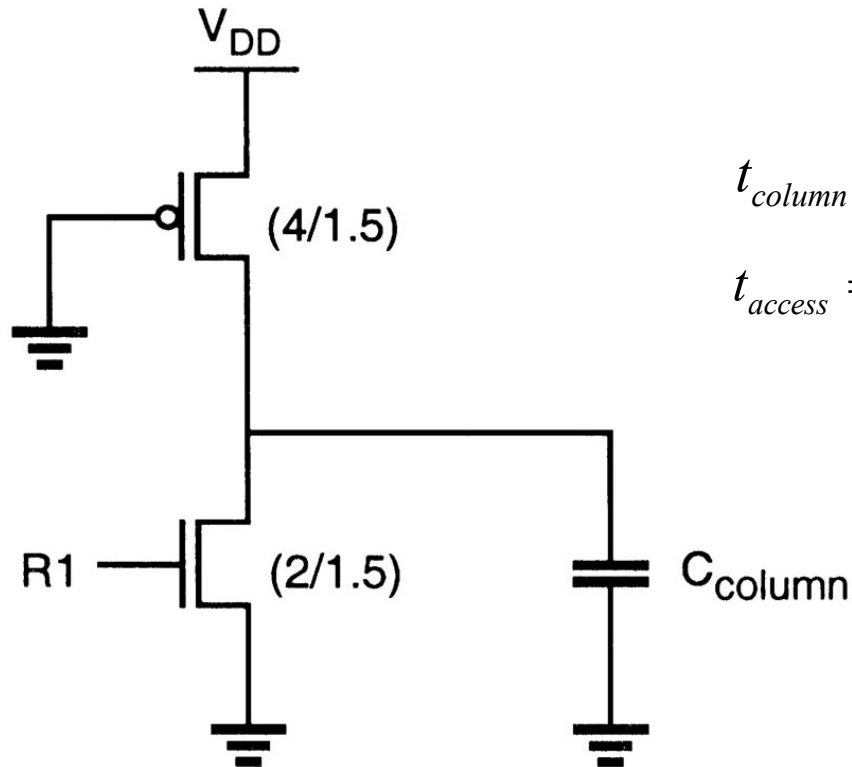
$$\approx 1.5pF$$

where $C_{gd,driver} + C_{db,driver} = 0.0118pF / \text{word line}$



Example 10.1(4)

- To calculate column access time, consider the worst-case signal propagation delay τ_{PHL} for below inverter

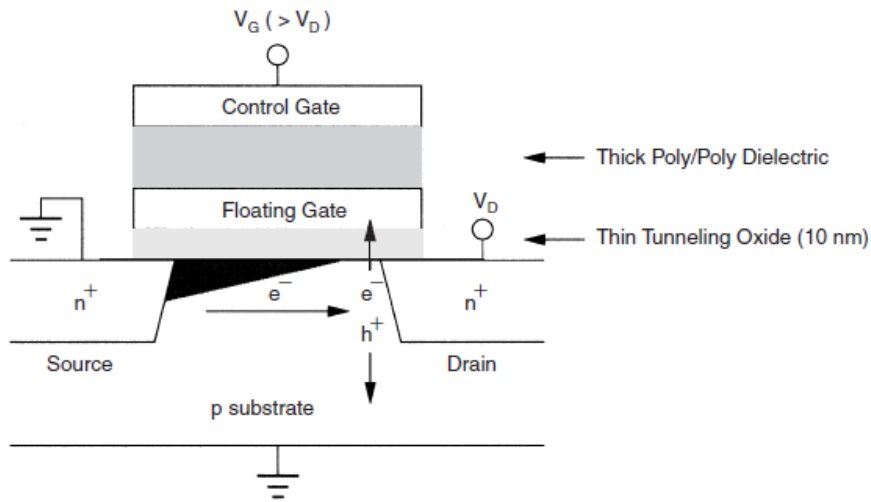


$$t_{\text{column}} = 18ns \quad (\text{using eq. 6.18: } t_{\text{PHL}})$$

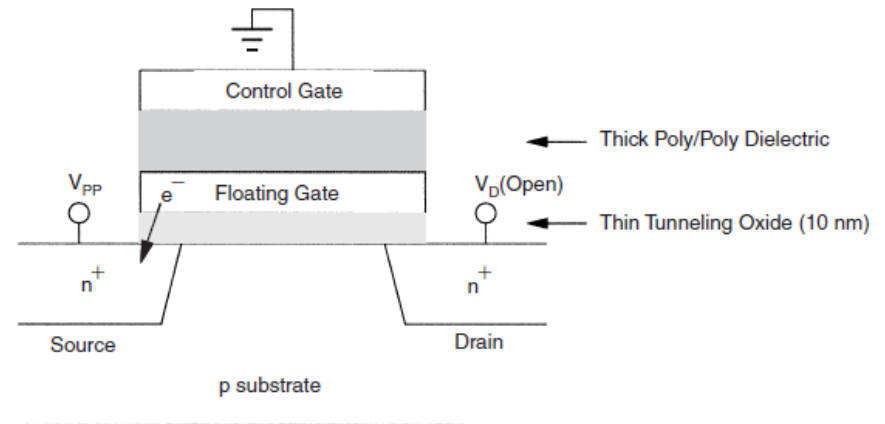
$$t_{\text{access}} = t_{\text{row}} + t_{\text{column}} = 38.5ns$$

10.5 Flash Memory

- ◆ One transistor with floating gate
- ◆ Memory cell can have two states (two threshold)
- ◆ Electron accumulated at the floating gate → higher threshold → "1" state
- ◆ Electron removed from the floating gate → lower threshold → "0" state

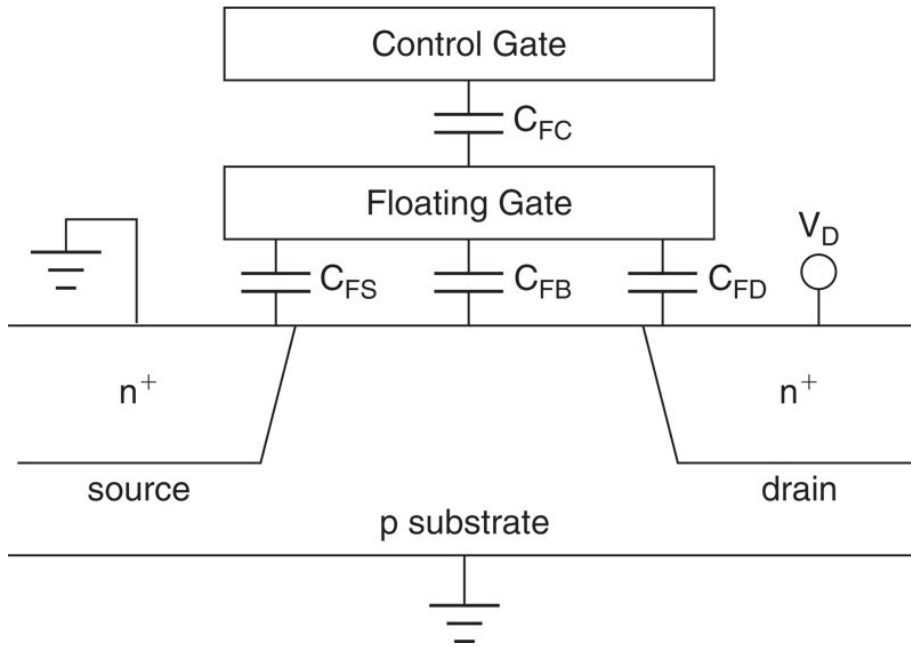


Hot electron injection mechanism
(Data programming)



Fowler-Nordheim tunneling mechanism
(Data erasing)

Equivalent Capacitive-Coupling Circuit



Q_{FC} : charge stored at floating gate

C_{total} : total cap.

C_{FC} : cap. between floating and control gate

C_{FS} , C_{FB} and C_{FD} : cap. between floating gate and source, bulk and drain

V_{CG} and V_D : voltage at control gate and drain

$V_T(FG)$: threshold voltage to turn on the floating gate transistor

- V_{FG} by capacitive coupling after V_{CG} & V_D applied

$$V_{FG} = \frac{Q_{FG}}{C_{total}} + \frac{C_{FC}}{C_{total}} V_{CG} + \frac{C_{FD}}{C_{total}} V_D$$

$$C_{total} = C_{FC} + C_{FS} + C_{FB} + C_{FD}$$

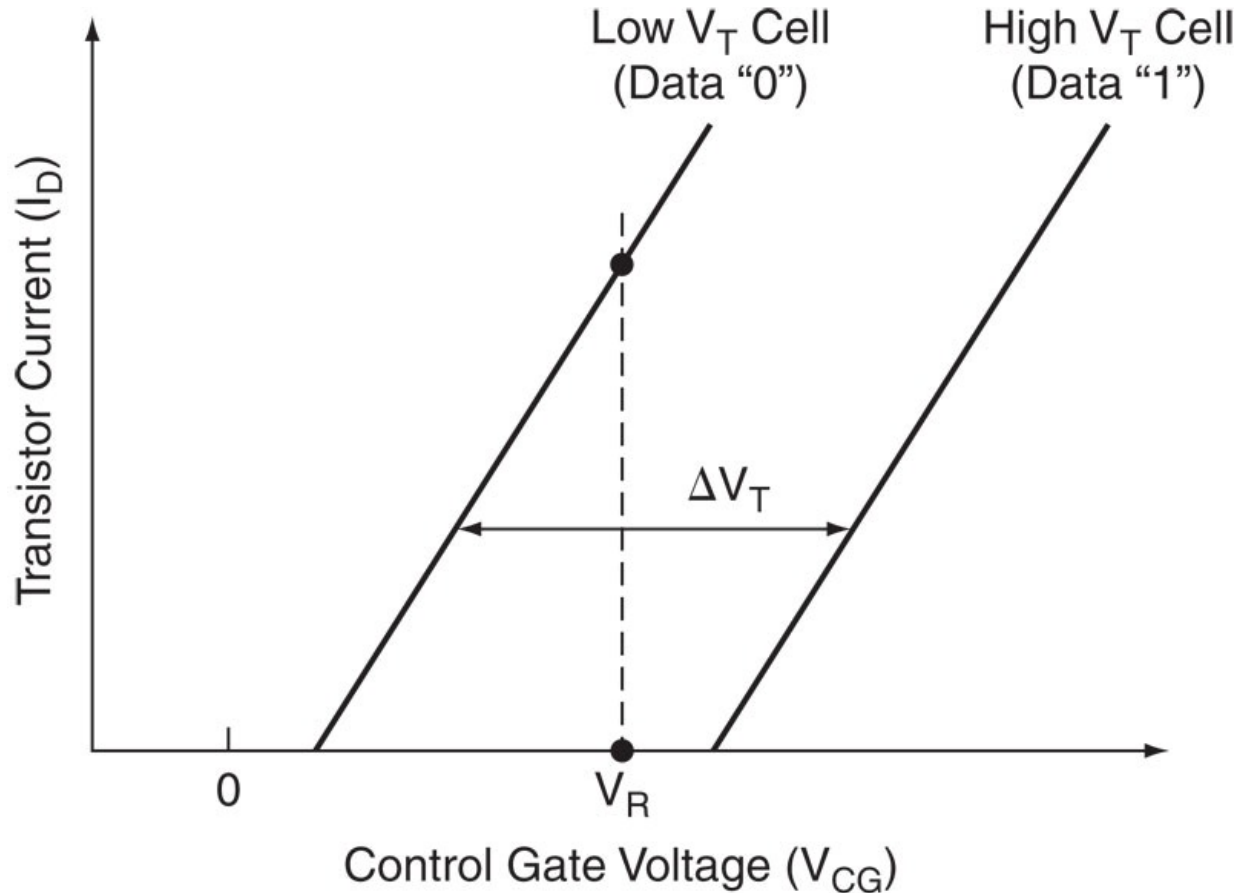
- min. V_{CG} to turn on the control gate transistor

$$V_T(CG) = \frac{C_{total}}{C_{FC}} V_T(FG) - \frac{Q_{FG}}{C_{FC}} - \frac{C_{FD}}{C_{FC}} V_D$$

$$\Delta V_T(CG) = -\frac{\Delta Q_{FG}}{C_{FC}}$$

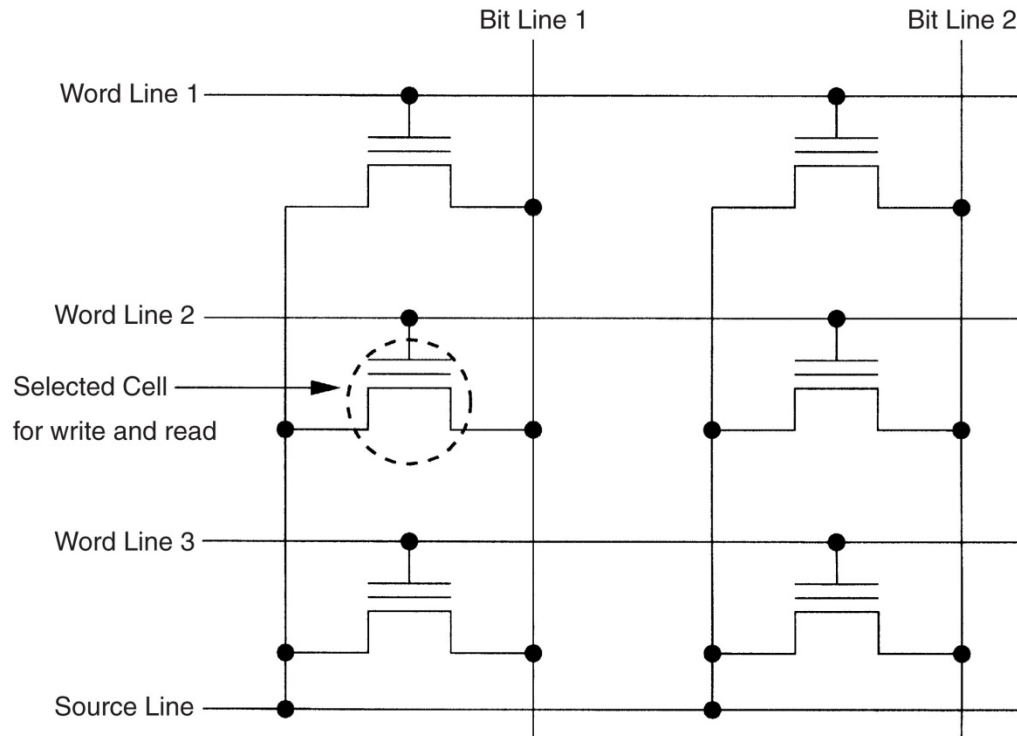
I-V Characteristic of Flash Memory

- ◆ Low and high threshold voltages for control gate voltage



NOR Flash Memory Cell

◆ Bias conditions and configuration of NOR Cells



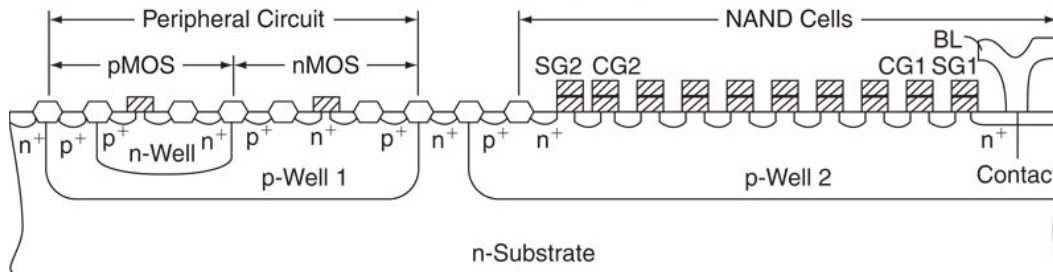
- ◆ F-N tunneling mechanism for erase operation
- ◆ Hot-electron injection mechanism for programming operation

Bias Conditions of NOR Cell

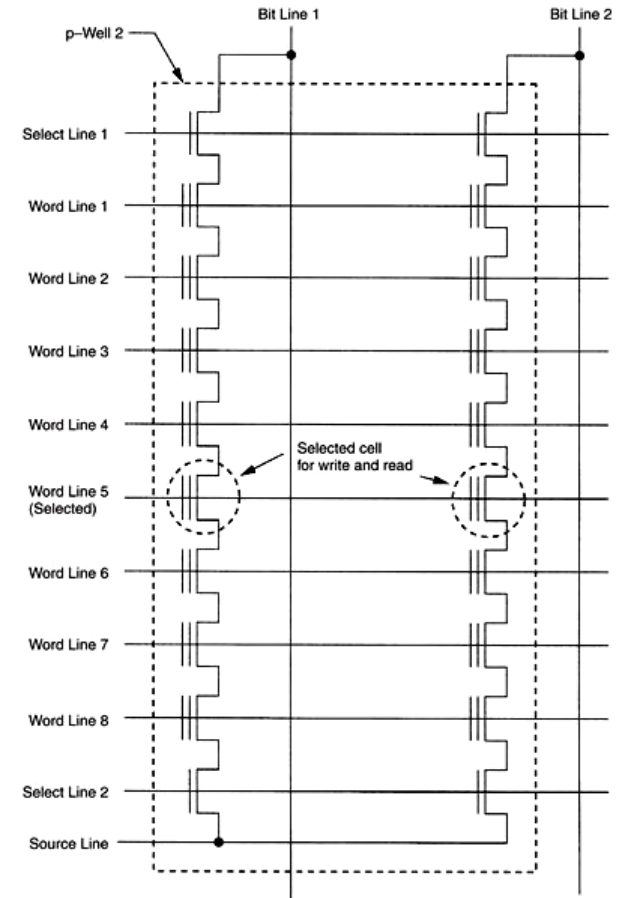
Signal	Operation		
	Erase	Programming	Read
Bit line 1	Open	6V	1V
Bit line 2	Open	0V	0V
Source line	12V	0V	0V
Word line 1	0V	0V	0V
Word line 2	0V	12V	5V
Word line 3	0V	0V	0V

NAND Flash Memory Cell

◆ Cross-section view and configuration of NAND cells



- ◆ F-N tunneling mechanism for erase
- ◆ F-N tunneling mechanism for program
- ◆ Slower programming and read speed but smaller area than NOR cell structure



Bias Conditions of NAND Cell

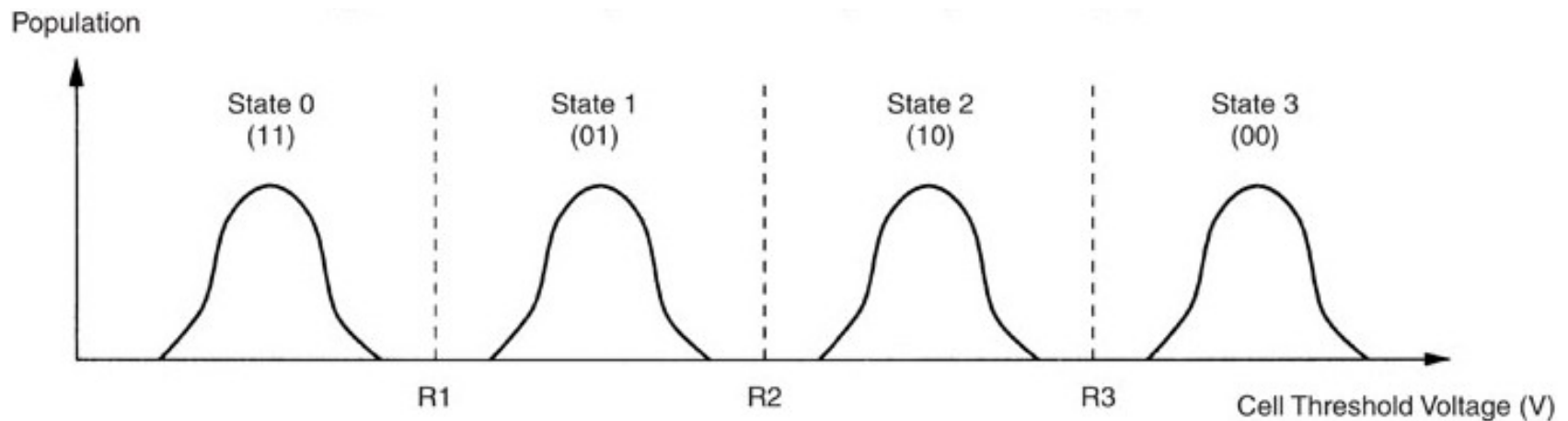
Signal	Operation		
	Erase	Programming	Read
Bit line 1	Open	0V	1V
Bit line 2	Open	0V	1V
Select line 1	Open	5V	5V
Word line 1	0V	10V	5V
Word line 2	0V	10V	5V
Word line 3	0V	10V	5V
Word line 4	0V	10V	5V
Word line 5	0V	20V	0V
Word line 6	0V	10V	5V
Word line 7	0V	10V	5V
Word line 8	0V	10V	5V
Select line 2	Open	0V	5V
Source line	Open	0V	0V
p-well 2	20V	0V	0V
n-sub	20V	0V	0V

Comparison between NOR and NAND

	NOR	NAND
Erase method	F-N tunneling	F-N tunneling
Programming method	Hot electron injection	F-N tunneling
Erase speed	Slow	Fast
Program speed	Fast	Slow
Read speed	Fast	Slow
Cell size	Large	Small
Scalability	Difficult	Easy
Application	Embedded system	Mass storage

Multilevel Cell Concept

- ◆ Effective memory density can be improved
- ◆ Possible state number limited by
 - Available charge range
 - Accuracy of programming and read operations
 - Disturbance of state over time

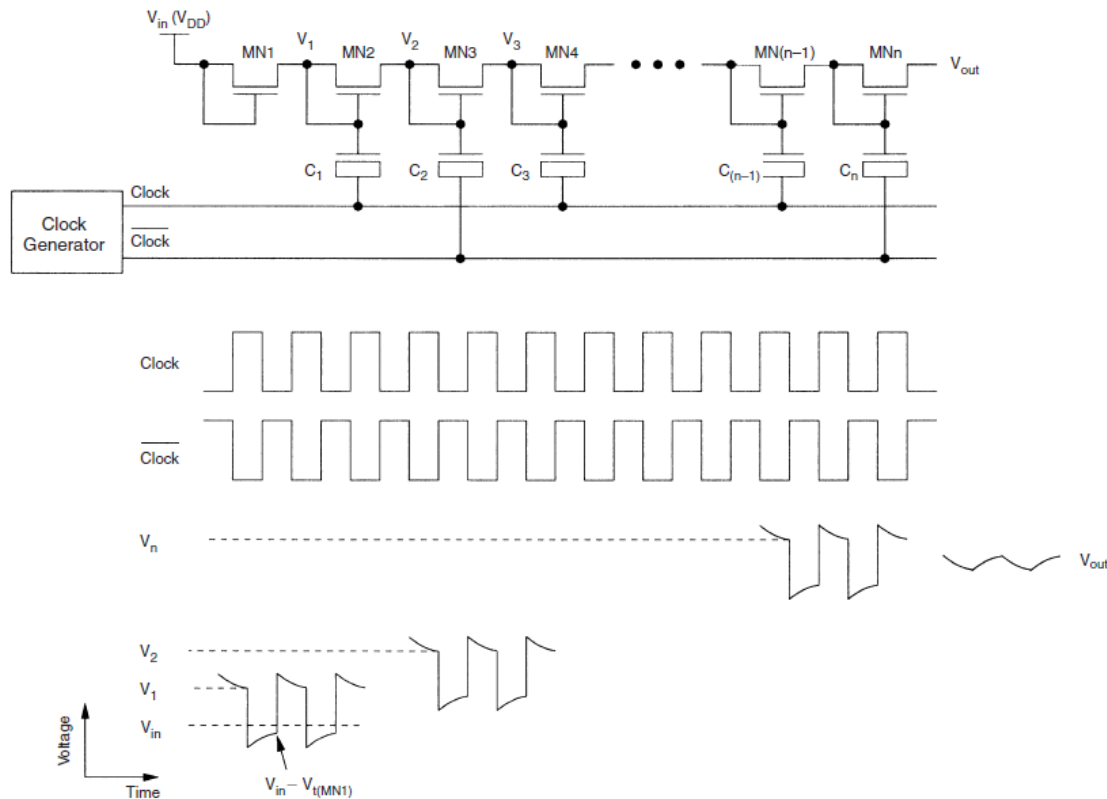


Threshold voltage distribution of 2bits/cell storage

Flash Memory Circuit

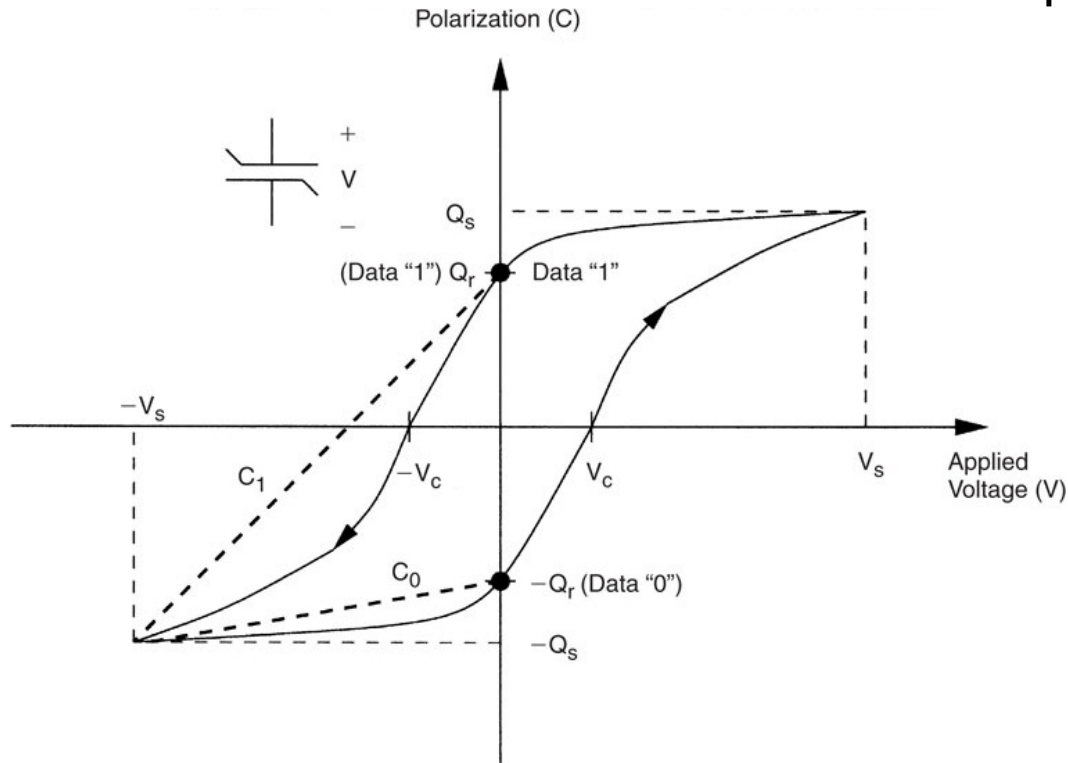
- ◆ On-chip charge pump used to generate programming voltage
- ◆ Chain of diode and cap. to charge or discharge each half cycle

$$V_{out} = V_{in} + (\gamma V_{DD} - V_T(MN1)) + \dots + (\gamma V_{DD} - V_T(MNn))$$



10.6 Ferroelectric Random Access Memory

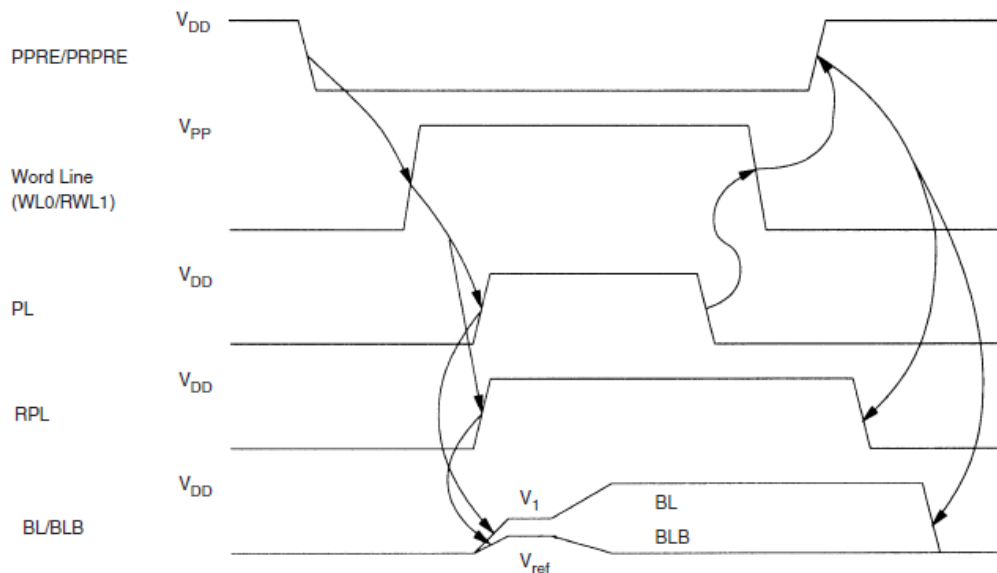
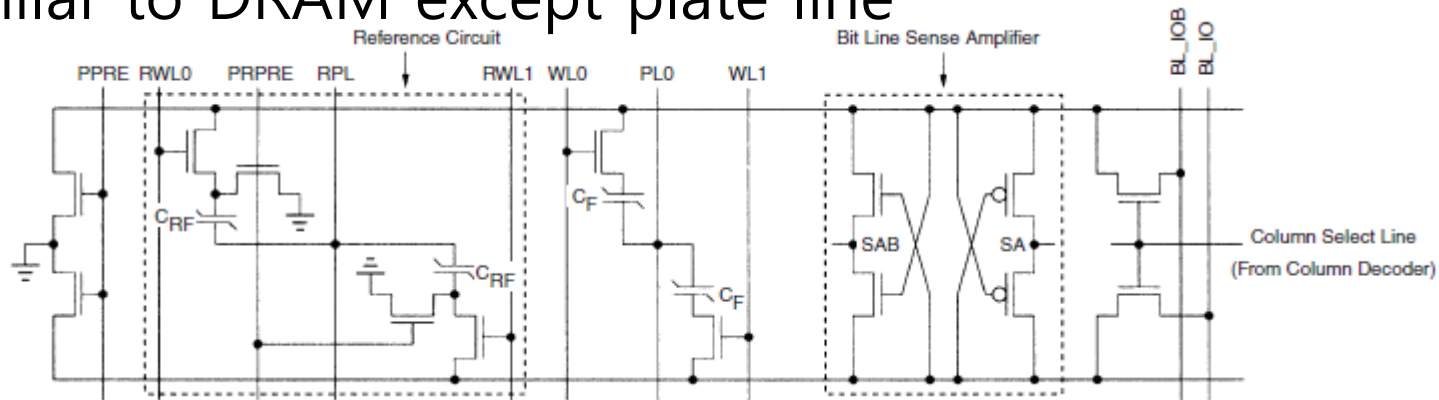
- ◆ Hysteresis characteristic of a ferroelectric cap.



- ◆ Total charge varies as function of applied voltage

Structure and Operation of FRAM

- ◆ Similar to DRAM except plate line



- Step-sensing scheme

$$\Delta V_1 = \frac{C_1}{C_1 + C_{BL}} V_{DD}$$

$$\Delta V_0 = \frac{C_0}{C_0 + C_{BL}} V_{DD}$$

C_1 and C_0 : linearly modeled ferroelectric cap

Problems of FRAM

- ◆ Step-sensing scheme cause reliability issues
 - Pulse sensing scheme also used with read speed penalty
- ◆ Fatigue
 - Capacitance charge gradually degraded with repeated use
- ◆ Imprint
 - Ferroelectric cap tends to stay at one state preferably when state maintained for a long time